Patent

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ABSTRACT

Workpiece with at least one functional face and a layer system deposited on at least a portion of the functional face as well as a structure pattern, which encompasses at least a portion of the layer system and which is comprised of at least one three dimensional micro structure (5) with structure depth **S**, characterized in that the deposited layer system is deposited with PVD, CVD or combined PCD/CVD processes, and the three dimensional micro structure (5) extends from the surface of the layer system (4) up into the workpiece, such that the latter is uncoated in a lower region of the micro structure (5).

IN THE ABSTRACT:

Please include the Abstract of the Disclosure, which is attached hereto on a separate sheet.